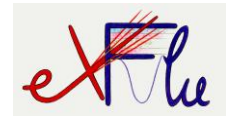


TCAD numerical simulation of irradiated Low-Gain Avalanche Diodes

T. Croci^(1,2), A. Morozzi⁽²⁾, F. Moscatelli^(2,3), V. Sola⁽⁴⁾, G. Borghi⁽⁵⁾, G. Paternoster⁽⁵⁾, M. Centis Vignali⁽⁵⁾, D. Passeri^(1,2)

- (1) Eng. Department – University of Perugia, Perugia, Italy
- (2) INFN of Perugia, Perugia, Italy
- (3) CNR-IOM, Perugia, Italy
- (4) INFN of Torino, Torino, Italy
- (5) Fondazione Bruno Kessler (FBK), Trento, Italy

This work has been supported by the Italian PRIN MIUR 2017 "4DInSiDe" research project and is held in collaboration with the INFN CSN5 "eXFlu" research project



Outline

- Motivations
- TCAD simulation of LGAD devices
 - ❑ Layout and doping profile
 - ❑ Physical models (e.g. avalanche) and parameters
- Methodology
 - ❑ Static (DC) and small-signal (AC) behavior
 - ❑ Transient response
- Application of the developed model (e.g. thin LGADs)

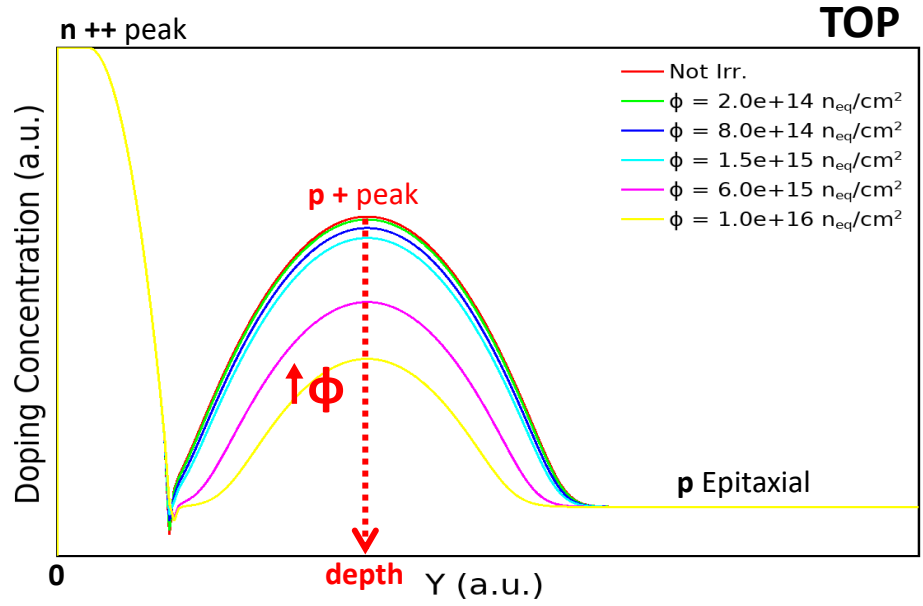
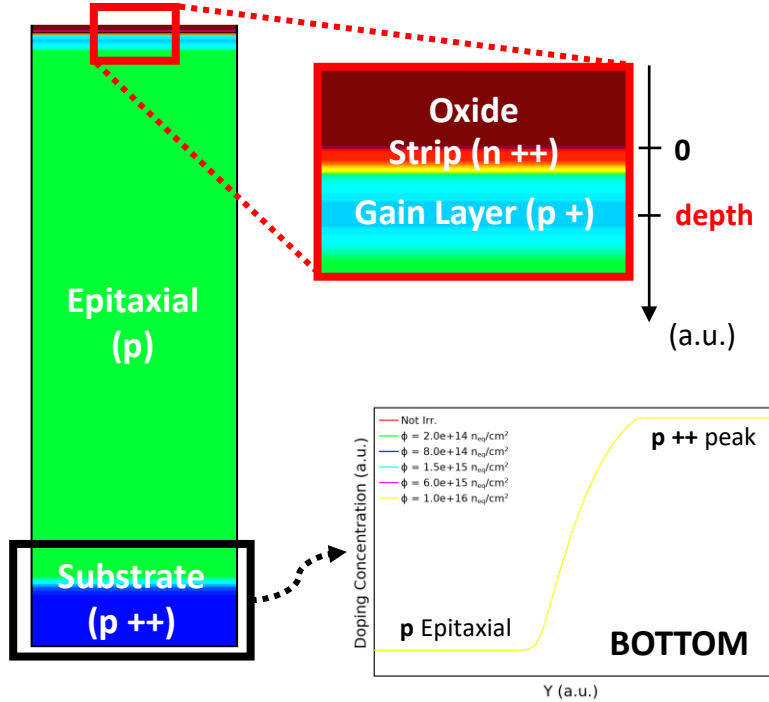
Motivations

- ✓ **Low-Gain Avalanche Diode (LGAD)**
- ✓ The **intrinsic multiplication of the charge** allows to **improve the signal to noise ratio**
=> **limitation of its drastic reduction with fluence.**
- ✓ Most promising devices **to cope with the high fluences** expected in the **future HEP experiments.**
- ✓ **Device-level simulation tools^[1]** for **predicting** the electrical behaviour and the charge collection properties **up to the highest particle fluences.**
- ✓ **Implementation** of a proper **radiation damage model** within the simulation environment.

[1] Synopsys© Sentaurus TCAD

TCAD simulation of LGAD devices (1/2)

✓ **Layout and doping profile**



TCAD simulation of LGAD devices (2/2)

✓ Physical models

✓ Generation/Recombination rate

- Shockley-Read-Hall (SRH), Band-To-Band Tunneling (BTBT), Auger
- **Avalanche Generation**
=> **impact ionization models**, such as *van Overstraeten-de Man*, *Okuto-Crowell*, *Massey*^[2], *UniBo*

✓ Carriers mobility variation doping and field dependent

✓ Physical parameters

- e-/h+ recombination lifetime
- surface recombination velocity

✓ Radiation damage models

✓ “New University of Perugia model”

- **Combined surface and bulk** TCAD damage modelling scheme^[3]
- Traps generation mechanism

✓ Acceptor removal mechanism

$$N_{GL}(\phi) = N_A(\mathbf{0})e^{-c\phi}$$

where

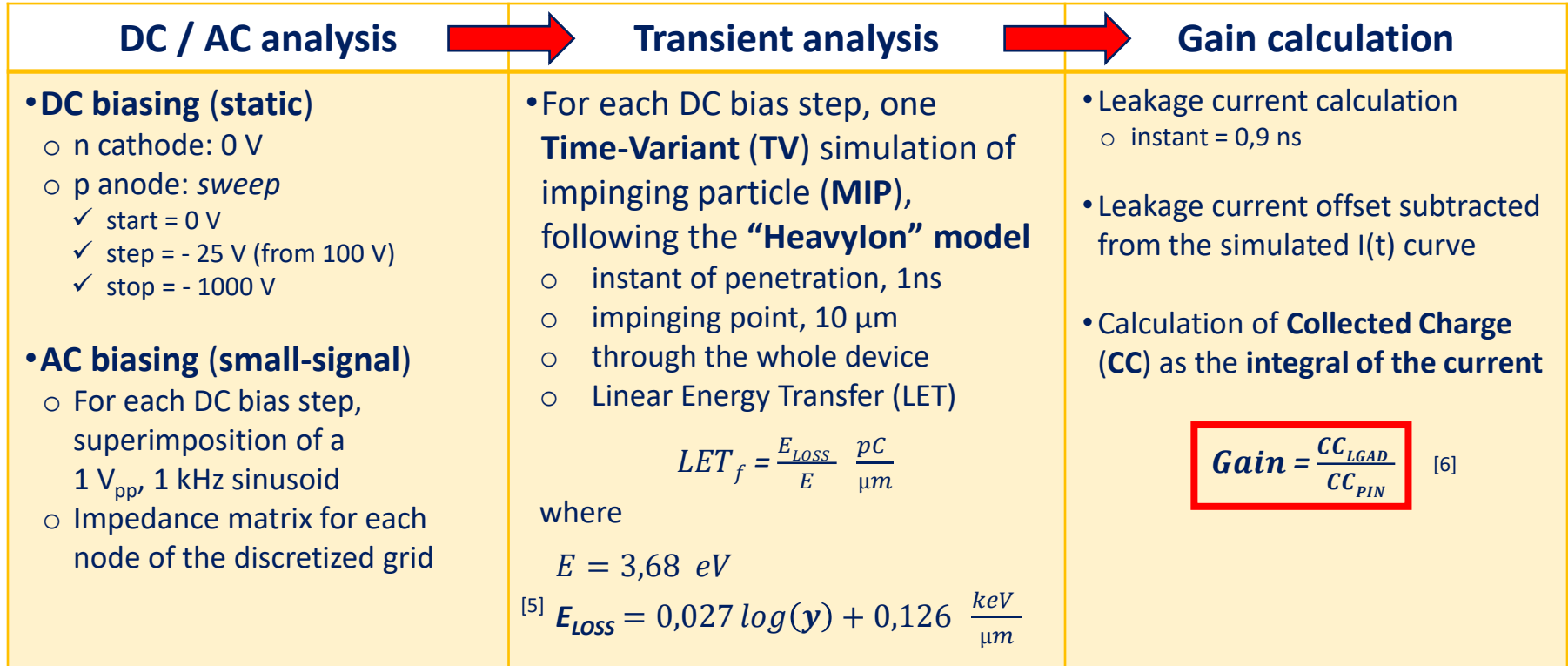
- **Gain Layer (GL)**
- **c**, removal rate, evaluated using the **Torino parameterization**^[4]

[2] M. Mandurrino et al., *Numerical Simulation of Charge Multiplication in Ultra-Fast Silicon Detectors (UFSD) and Comparison with Experimental Data*, IEEE, 2017

[3] AIDA2020 report, *TCAD radiation damage model - CERN Document Server*

[4] see M. Ferrero talk

Methodology

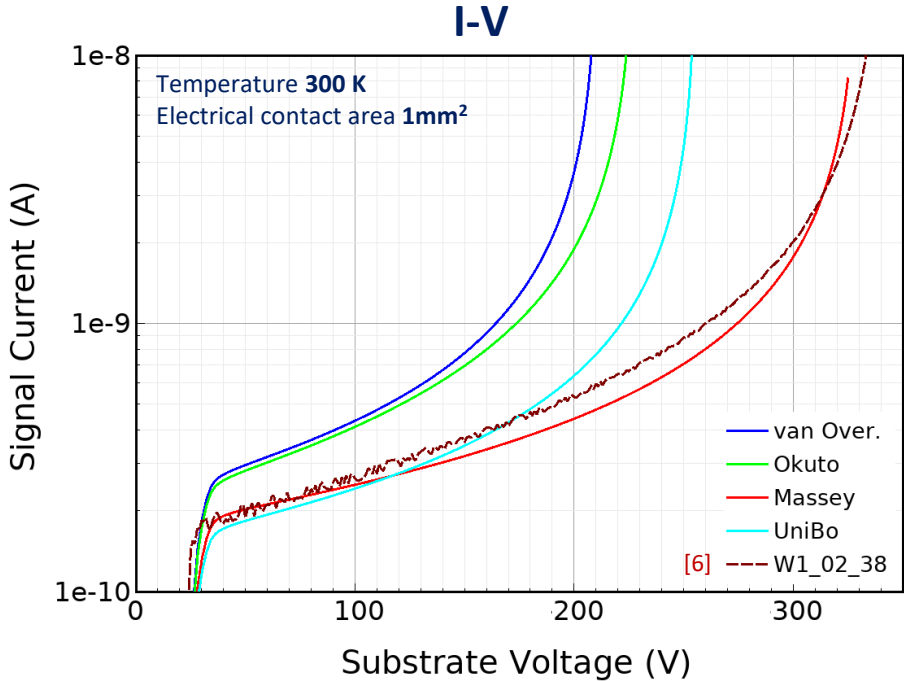


[5] S. Meroli et al., *Energy loss measurement for charged particles in very thin silicon layers*, JINST 6 P06013, 2011

[6] V. Sola et al., *First FBK production of 50 μm ultra-fast silicon detectors*, Nucl. Instrum. Methods Phys. Res. A, 2019

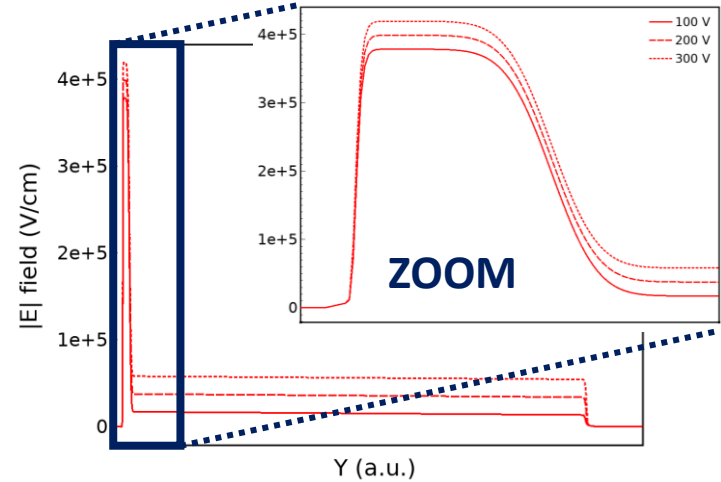
Analysis of different avalanche models

✓ Simulation results, before irradiation



Good agreement with experimental data for **Massey** model

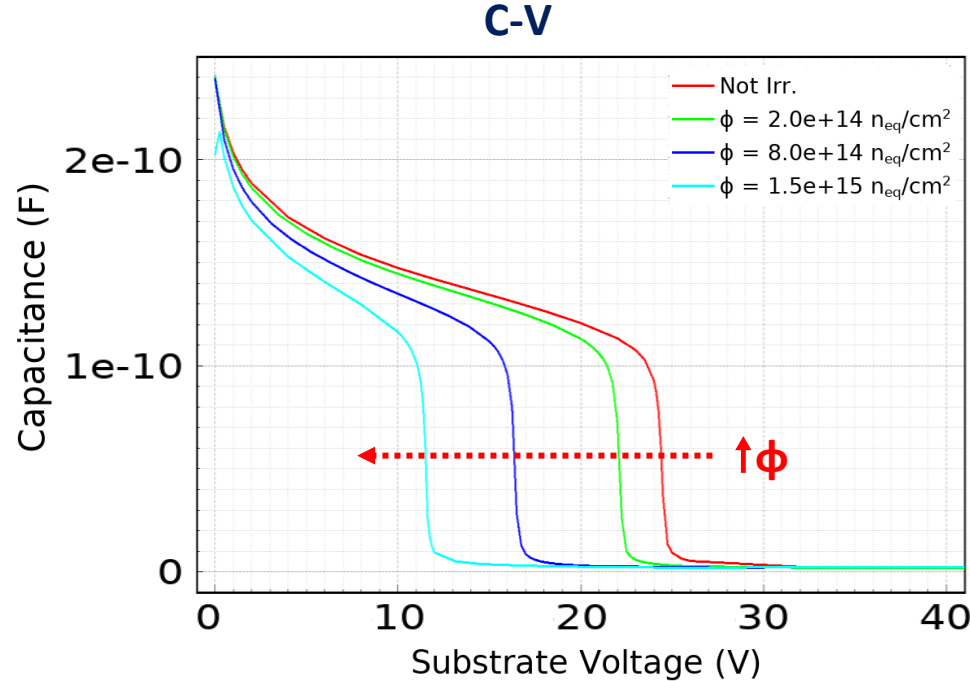
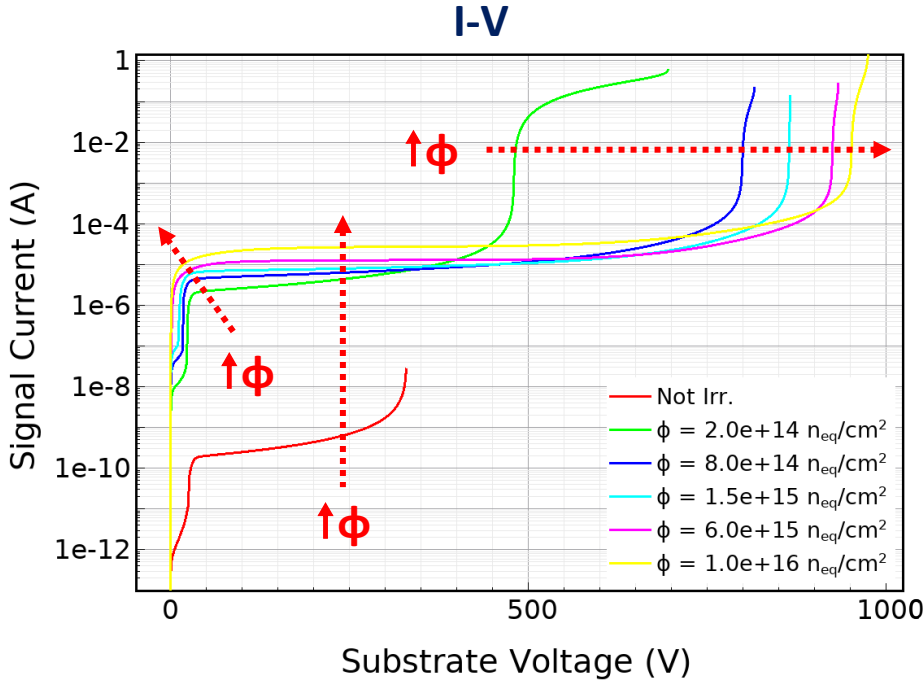
Cut of the electric field for different V_{bias}



[6] V. Sola et al., *First FBK production of 50 μm ultra-fast silicon detectors*, Nucl. Instrum. Methods Phys. Res. A, 2019

Static (DC) and small-signal (AC) behavior (1/6)

✓ Simulation results, before and after irradiation



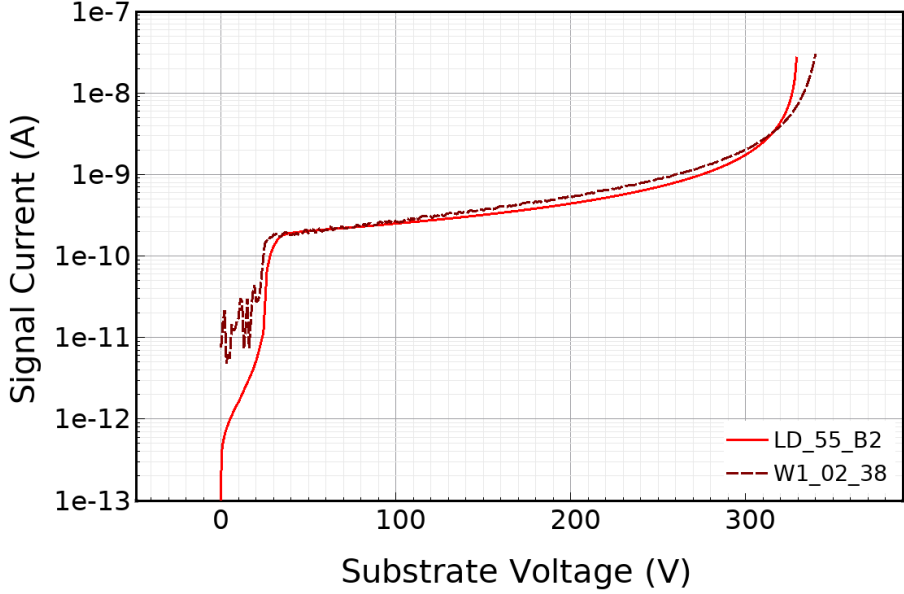
Massey model. Temperature 300 K. Electrical contact area 1mm²

Static (DC) and small-signal (AC) behavior (2/6)

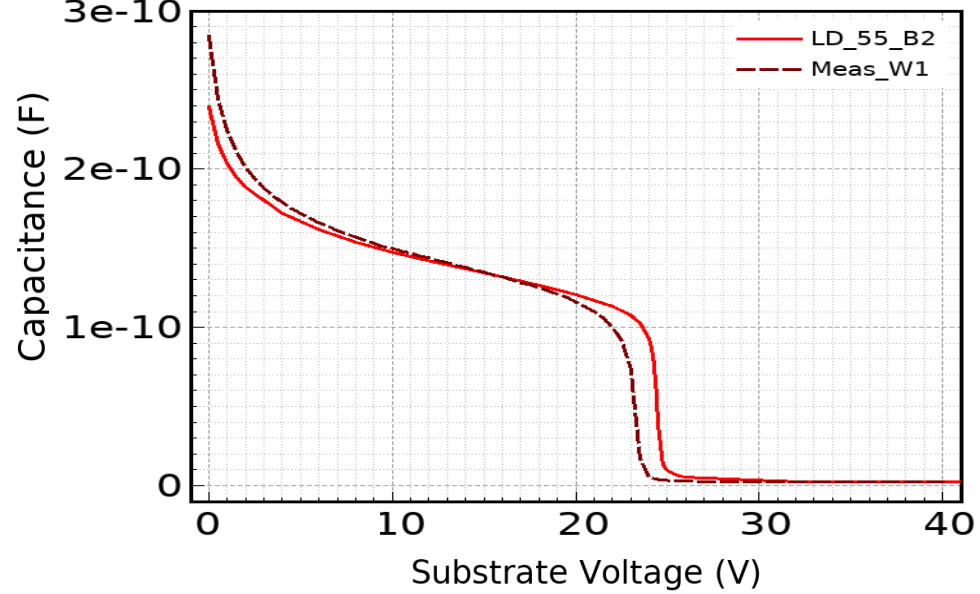
✓ Comparison with experimental data, before irradiation

Good agreement!

I-V



C-V

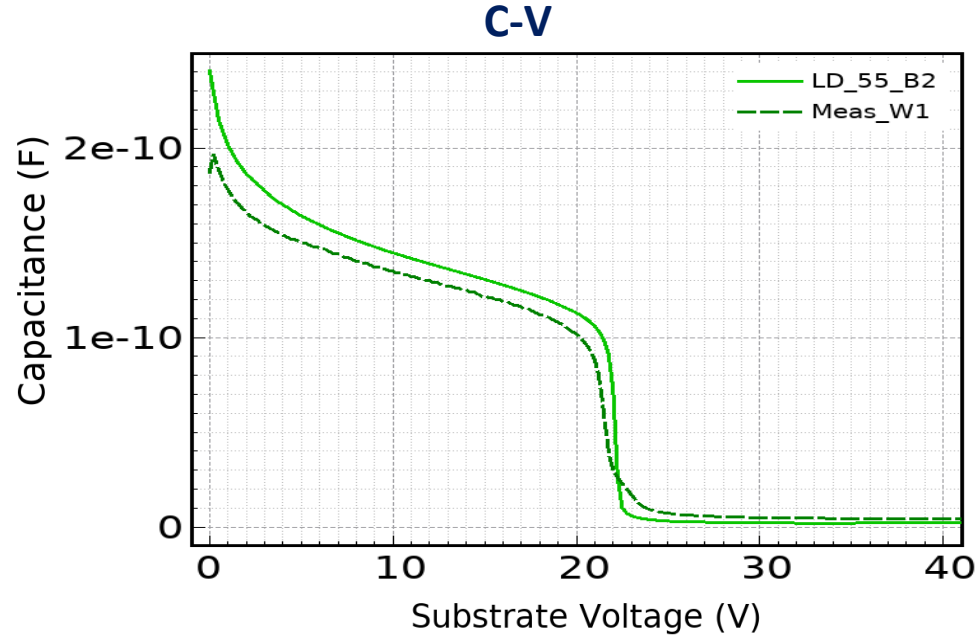
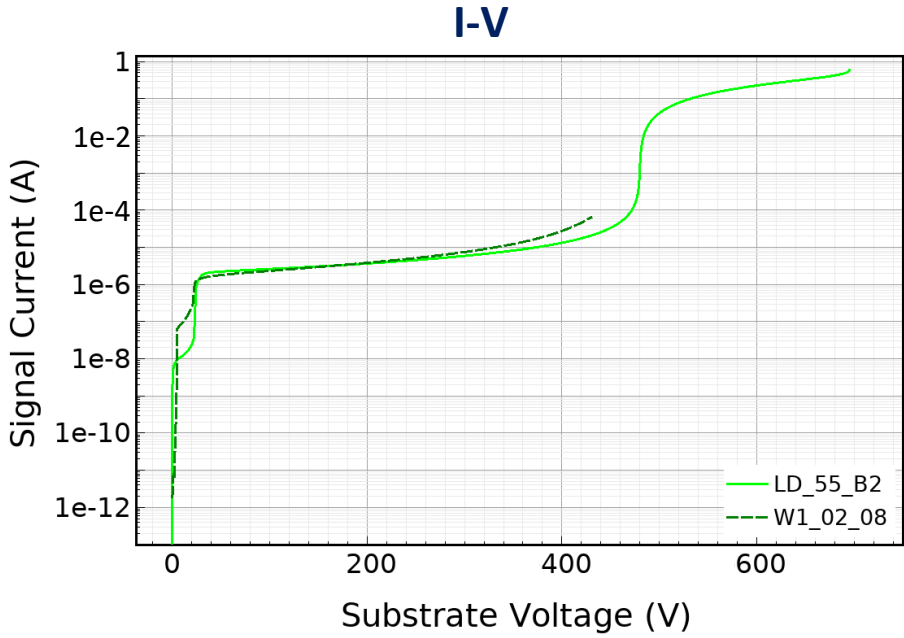


Massey model. Temperature 300 K. Electrical contact area 1mm²

Static (DC) and small-signal (AC) behavior (3/6)

✓ Comparison with experimental data, fluence $2.0e14 \text{ n}_{eq}/\text{cm}^2$

Good agreement!



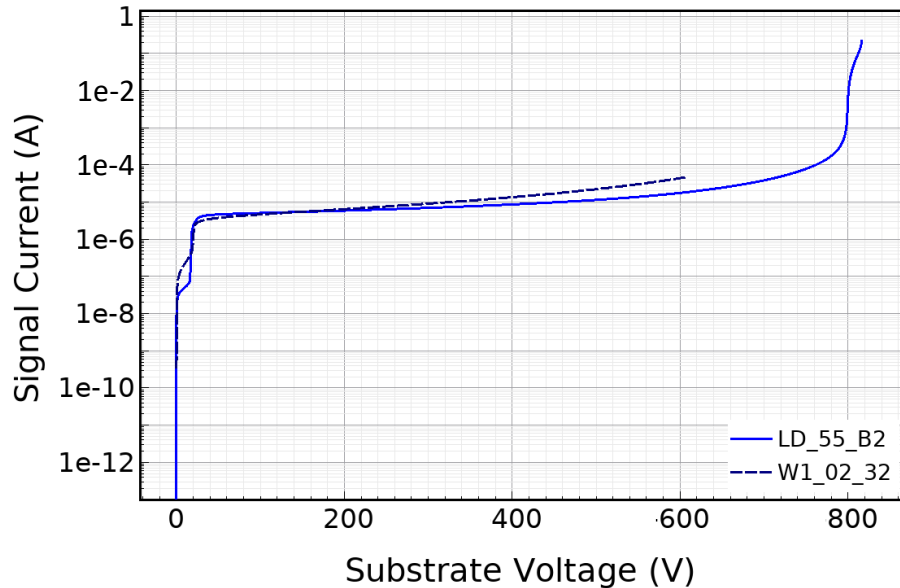
Massey model. Temperature **300 K**. Electrical contact area **1mm²**

Static (DC) and small-signal (AC) behavior (4/6)

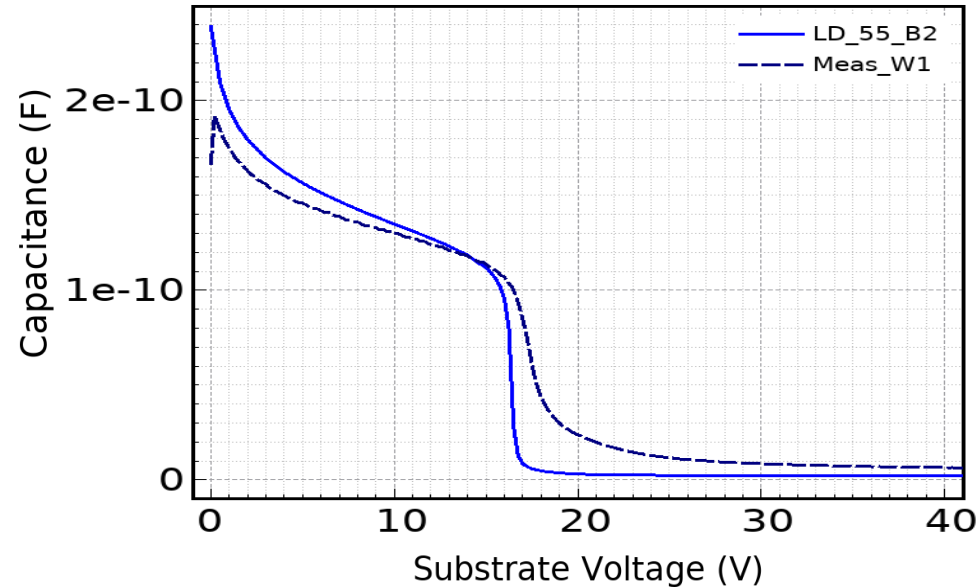
✓ Comparison with experimental data, fluence $8.0e14 \text{ n}_{\text{eq}}/\text{cm}^2$

Good agreement!

I-V



C-V



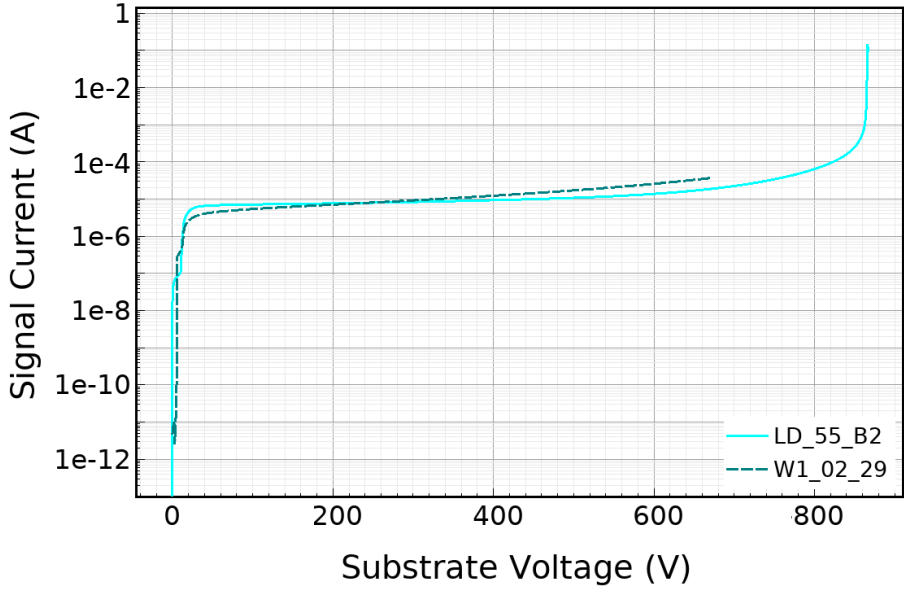
Massey model. Temperature **300 K**. Electrical contact area **1mm²**

Static (DC) and small-signal (AC) behavior (5/6)

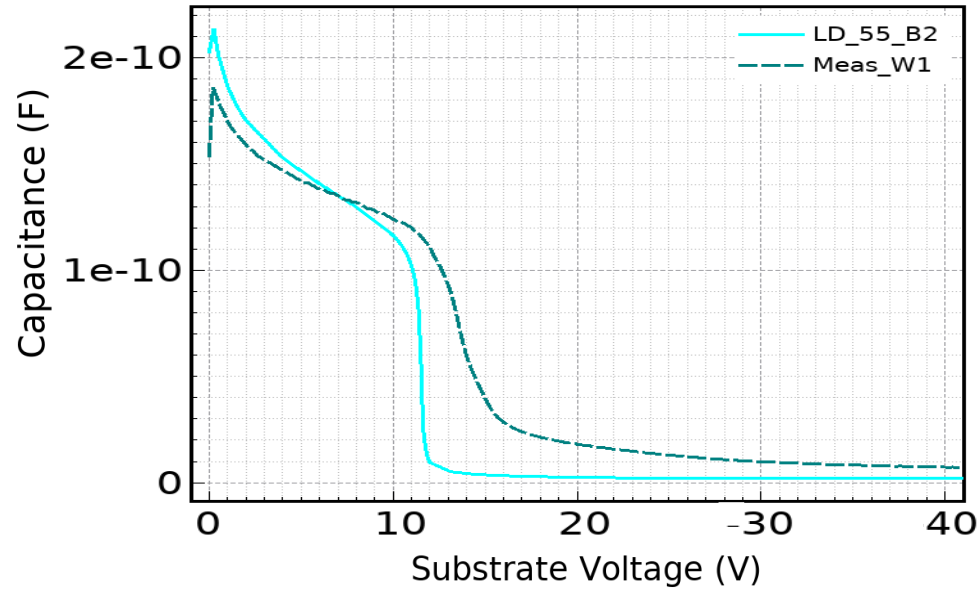
✓ Comparison with experimental data, fluence $1.5e15 \text{ n}_{eq}/\text{cm}^2$

Good agreement!

I-V



C-V



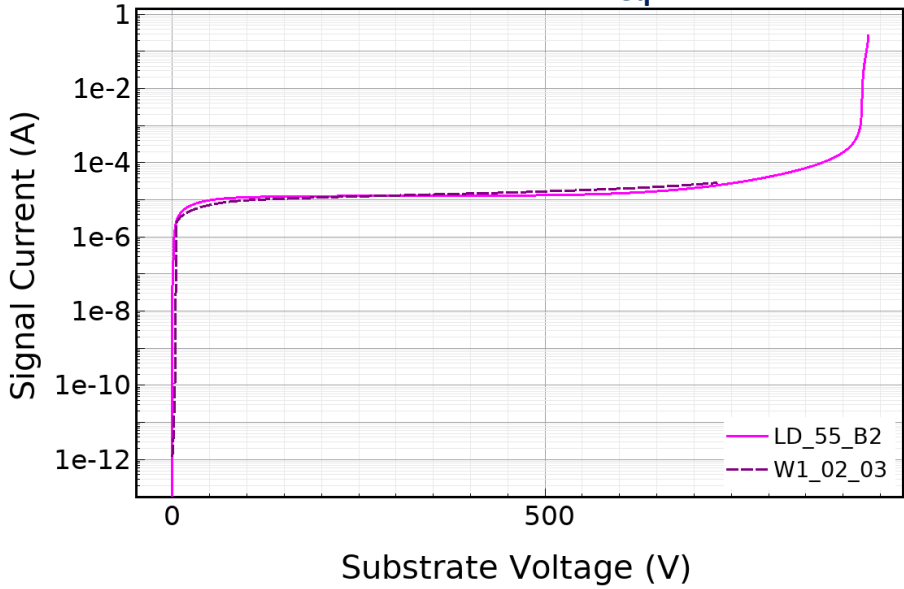
Massey model. Temperature **300 K**. Electrical contact area **1mm²**

Static (DC) and small-signal (AC) behavior (6/6)

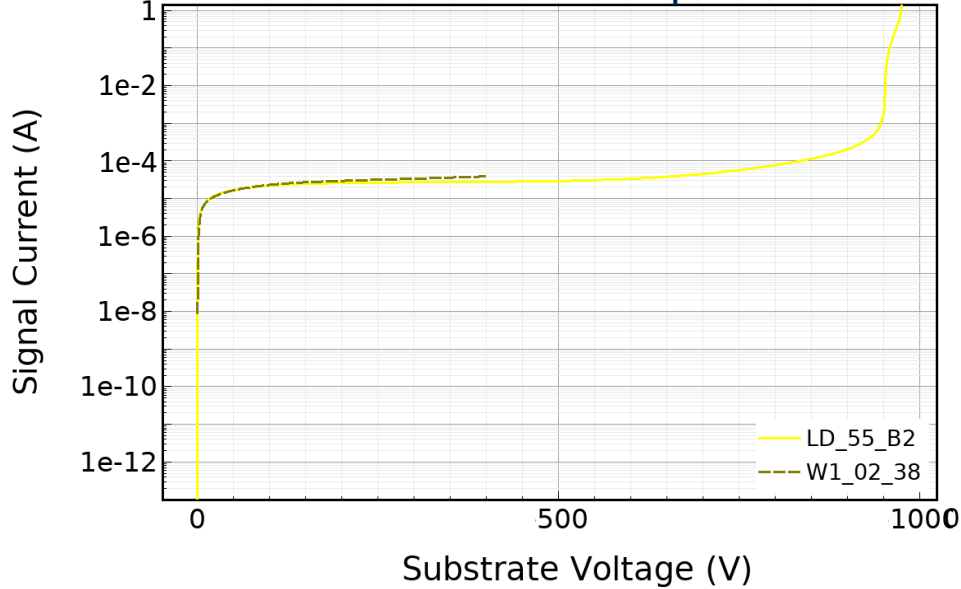
✓ Comparison with experimental data, after irradiation

Good agreement!

I-V, fluence $6.0e15 \text{ n}_{eq}/\text{cm}^2$



I-V, fluence $1.0e16 \text{ n}_{eq}/\text{cm}^2$



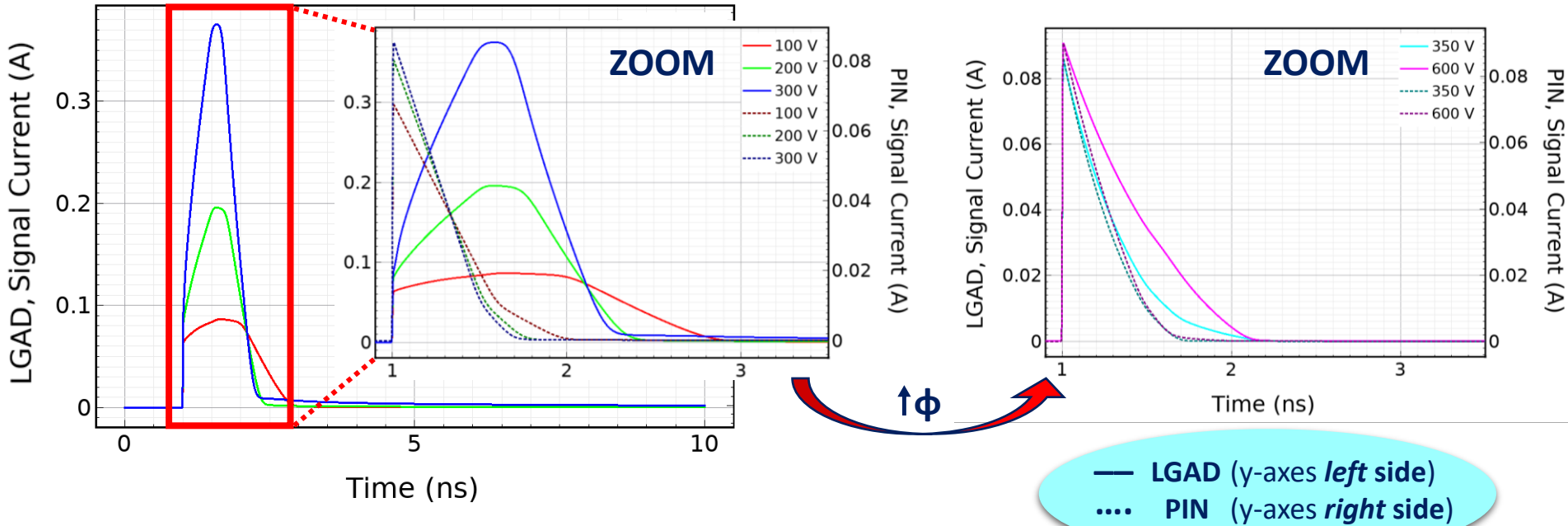
Massey model. Temperature **300 K**. Electrical contact area **1mm²**

Transient response

✓ Comparison between **LGAD** and **PIN** response to the **MIP** for different V_{bias}

I-t, before irradiation

I-t, fluence $1.5e15 n_{eq}/cm^2$



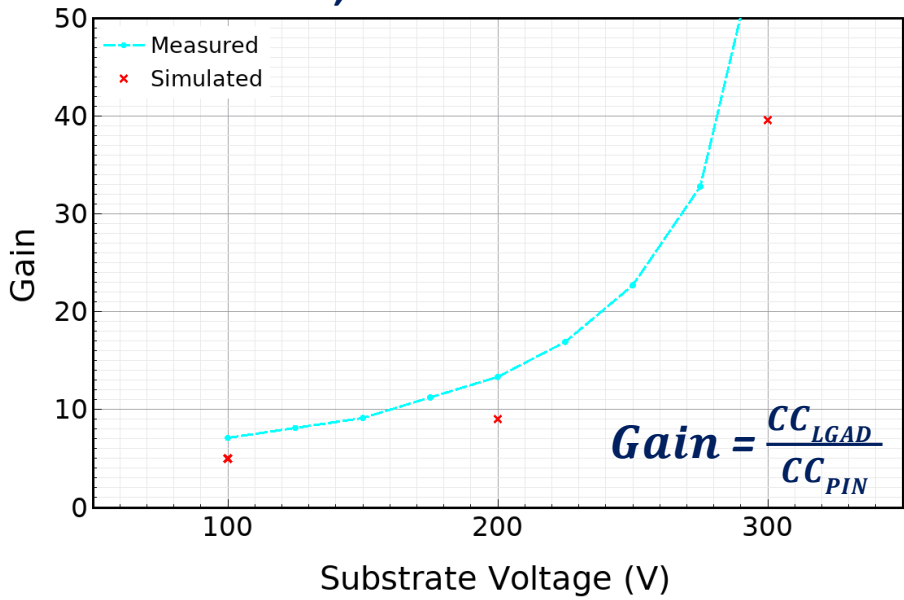
Massey model. Temperature **300 K**. Electrical contact area **1mm²**

Gain calculation

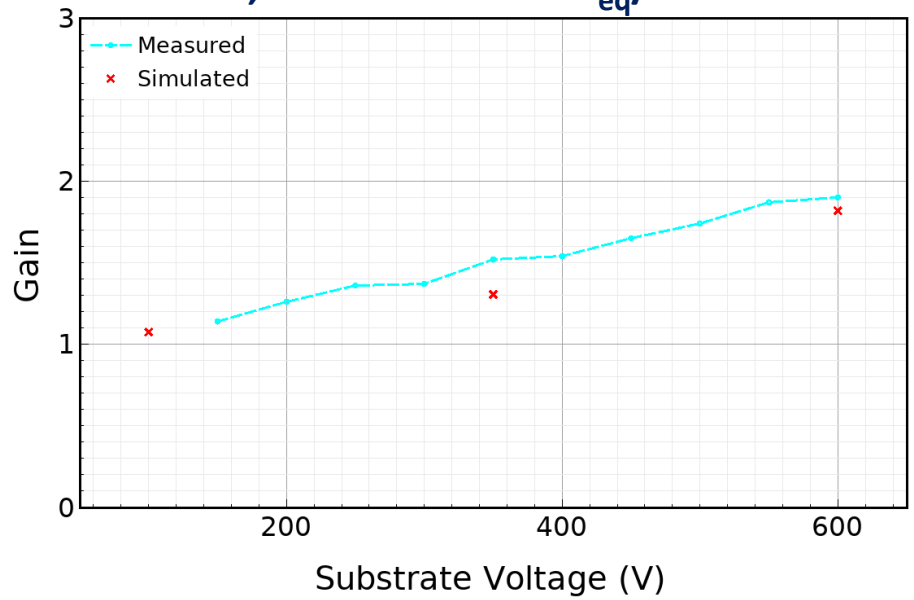
✓ Estimated error on data $\pm 10\%$

Good agreement!

G-V, before irradiation



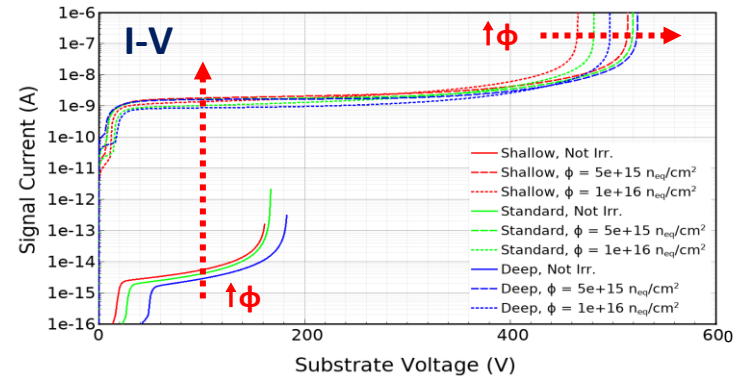
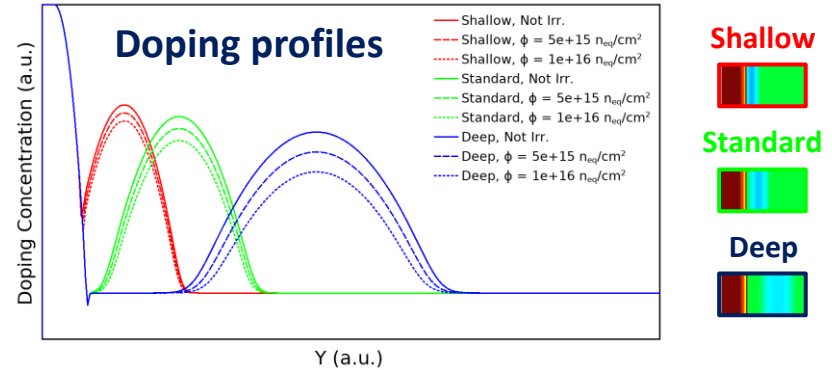
G-V, fluence $1.5e15 n_{eq}/cm^2$



Massey model. Temperature **300 K**. Electrical contact area **1mm²**

Application of the developed model

- ✓ **Thin wafers** recently produced by **FBK**
 - thickness 25 and 35 μm [7]
- ✓ **TCAD simulations** very useful to
 - **compare the results with the experimental data, before and after irradiation**
(irradiation campaign just completed at the Ljubljana JSI facility up to $1.0\text{e}17 \text{ n}_{\text{eq}}/\text{cm}^2$)
 - **designing the future productions of thin LGADs for extreme fluences**



[7] V. Sola et al., *First results from thin silicon sensors for extreme fluences*, 37th RD50 Workshop, Zagreb, Croatia, 2020

Massey model, Temperature **300 K**.

Conclusions

- ✓ **Strategy** for the numerical simulation of LGAD devices.
- ✓ **Results** obtained under **different operative conditions** (device biasing, fluence).
- ✓ **Good agreement** between simulation predictions and experimental data **for both non-irradiated and irradiated** LGAD device.
- ✓ **Combination** of “new University of Perugia TCAD model” and the “acceptor removal” analytical model is used to simulate the **radiation damage effects**
 - => successful **description** of the **decrease in gain with** an increase in **fluence**.
- ✓ **Application** of the validated simulation framework **for the prediction** of **different design options/detector geometries** (e.g. thin sensors) behavior
 - => optimization for their **use in the future HEP experiments**.

Thank you for the attention!

**16th Workshop on
Advanced Silicon Radiation Detectors
Trento, 16-18 February 2021**

BACKUP SLIDES

Low-Gain Avalanche Diodes (LGADs)

- Most promising devices to cope with the high spatial density of particles hits due to the increasing radiation fluence expected in the HL-LHC at CERN.
- **LGAD structure:** pin diode with the additional inclusion of a p+-type layer just below the n-contact, which is commonly called *multiplication layer*.
- By applying a reverse-bias, this layer is responsible for a **multiplication of carriers**.

$$G_{\text{aval}} = \alpha_n n v_n + \alpha_p p v_p \qquad \alpha = \frac{E}{E_{th}} e^{-\frac{E_i}{E}}$$

- By accurately choosing the **peak and shape of the implanted p+ profile**, it is possible to control the **avalanche mechanism** in order to obtain the required internal gain with a sufficiently high breakdown voltage.
- One of the best tools **for predicting the behaviour of the avalanche process** is **device-level simulation**

Technology-CAD simulations

- **TCAD simulation tools** solve fundamental, physical partial differential equations, such as diffusion and transport equation for discretized geometries (finite element meshing).
- This deep physical approach gives TCAD simulation **predictive accuracy**.
- **Synopsys© Sentaurus TCAD**

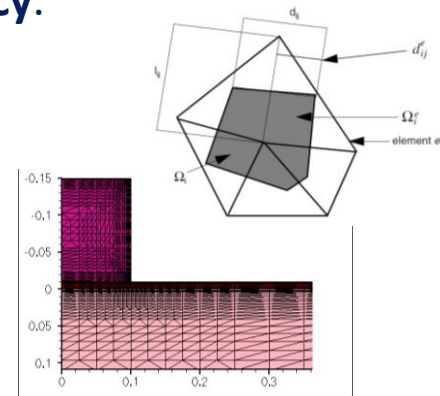
$$\left\{ \begin{array}{l} \nabla \cdot (-\varepsilon_s \nabla \phi) = q (N_D^+ - N_A^- + p - n) \\ \frac{\partial n}{\partial t} - \frac{1}{q} \nabla \cdot \vec{J}_n = U_n \\ \frac{\partial p}{\partial t} + \frac{1}{q} \nabla \cdot \vec{J}_p = U_p \end{array} \right.$$

$$\vec{J}_n, \vec{J}_p$$

Poisson

Electron continuity

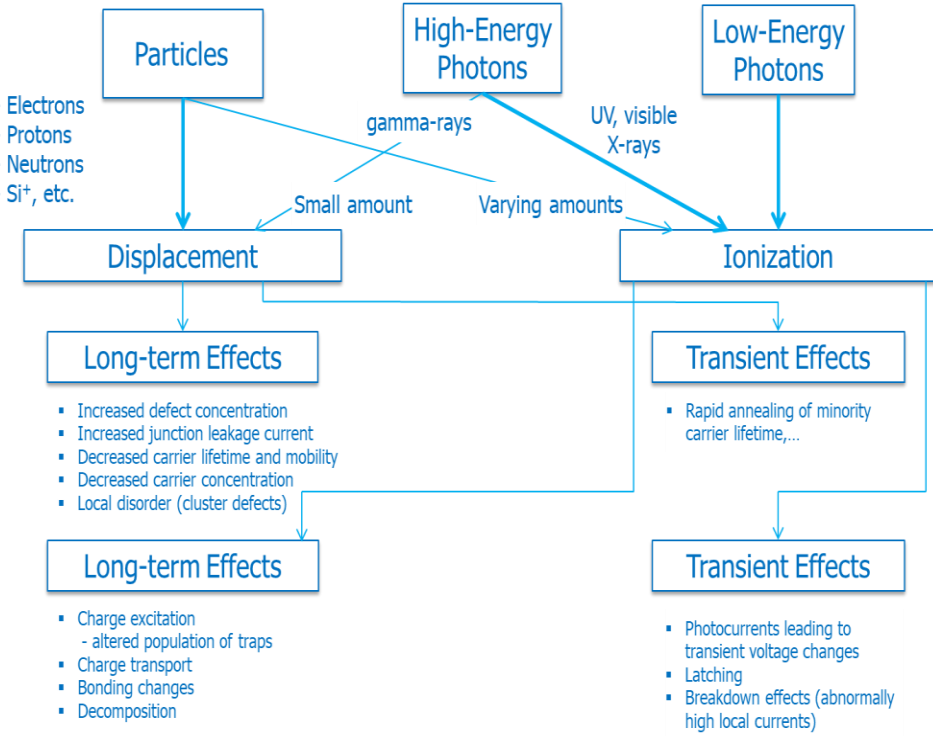
Hole continuity



$$U_{n,p} = G - R$$

Radiation damage effects (1/2)

✓ **in silicon sensors**



Two main **types of radiation damage** in detectors materials:

- **SURFACE damage** => Ionization
 - ✓ Build-up of trapped charge within the oxide;
 - ✓ Bulk oxide traps increase;
 - ✓ Interface traps increase;
 - ✓ Q_{OX} , N_{IT} .
- **BULK damage** => Atomic displacement
 - ✓ Silicon lattice defect generations;
 - ✓ Point and cluster defects;
 - ✓ Deep-level trap states increase;
 - ✓ Change of effective doping concentration;
 - ✓ N_T .

Radiation damage effects (2/2)

✓ in LGAD devices

- **Acceptor removal mechanism** [1]: the active (substitutionals) doping elements are partially removed from their lattice sites due to the ionizing radiation and then de-activated after a kick-out reaction (Watkins mechanism [2]) that produces ion-acceptor complexes (interstitials)
- Transformation of electrically active acceptors into defect complexes that no longer have dopant properties
- This has been recently suggested as a possible explanation for the significant degradation of gain (charge multiplication) observed on LGAD devices after irradiation.

(1) G. Kramberger, M. Baselga et al., *J. Inst.*, vol. 10, no. 7, p. P07006, 2015

(2) G. D. Watkins, *Defects and Their Structure in Non-metallic Solids*, B. Henderson and A. E. Hughes, Eds. New York: Plenum, 1975

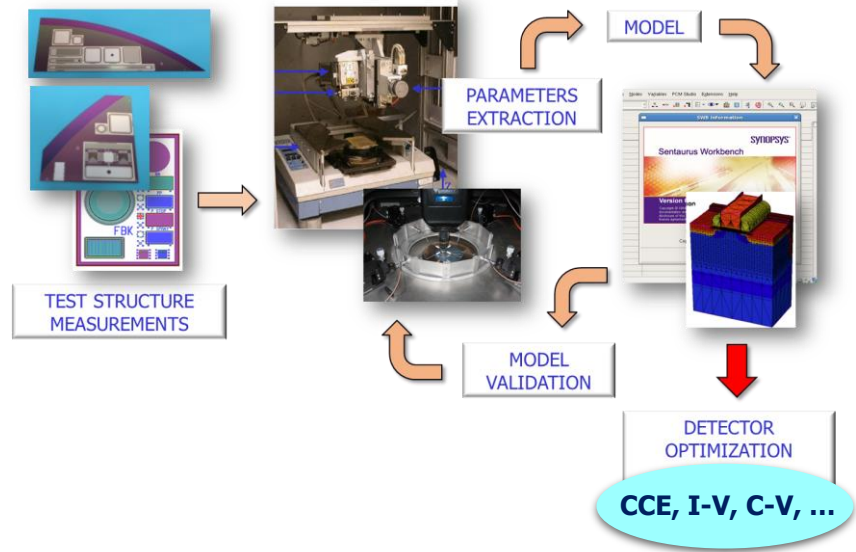
TCAD radiation damage models used

- **“New University of Perugia model”**
 - ✓ Combined surface and bulk TCAD damage modelling scheme
 - ✓ Traps generation mechanism
- **Acceptor removal mechanism**

$$N_{GL}(\phi) = NA(0)e^{-c\phi}$$

where

- **Gain Layer (GL)**
- **c**, removal rate, evaluated using the **Turin parameterization**



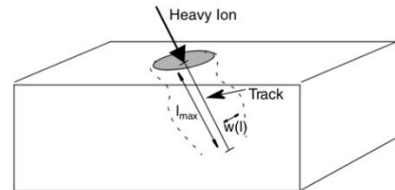
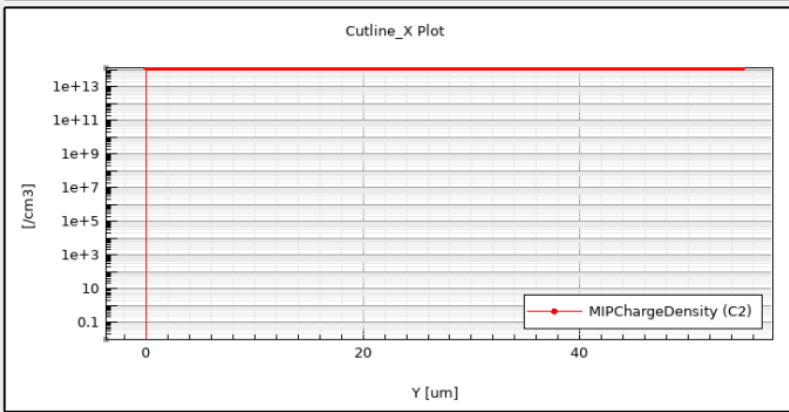
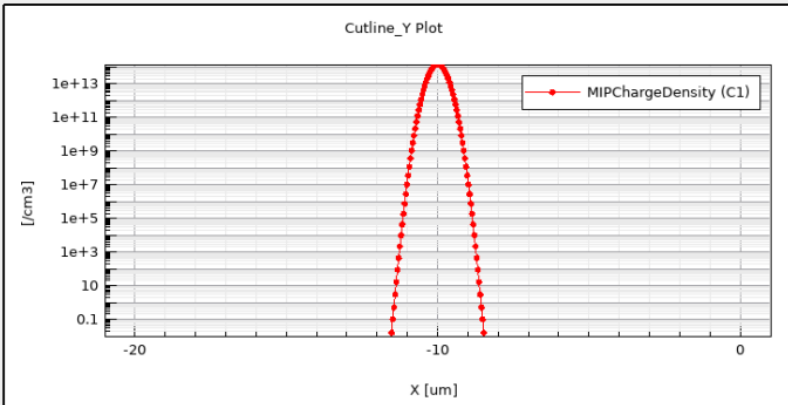
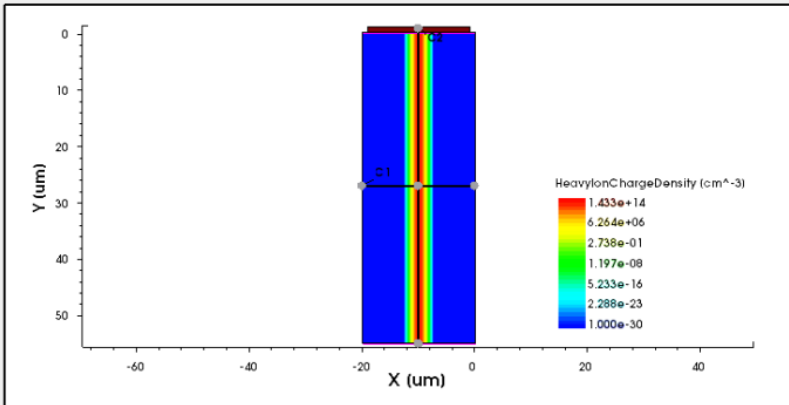
Surface damage (+ Q_{ox})

Type	Energy (eV)	Band width (eV)	Conc. (cm ⁻²)
Acceptor	E _C ≤ E _T ≤ E _C -0.56	0.56	D _{IT} = D _{IT} (Φ)
Donor	E _V ≤ E _T ≤ E _V +0.6	0.60	D _{IT} = D _{IT} (Φ)

Bulk damage

Type	Energy (eV)	η (cm ⁻¹)	σ _n (cm ²)	σ _p (cm ²)
Donor	E _C - 0.23	0.006	2.3×10 ⁻¹⁴	2.3×10 ⁻¹⁵
Acceptor	E _C - 0.42	1.6	1×10 ⁻¹⁵	1×10 ⁻¹⁴
Acceptor	E _C - 0.46	0.9	7×10 ⁻¹⁴	7×10 ⁻¹³

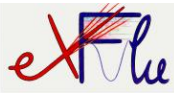
Transient response: "HeavyIon" model



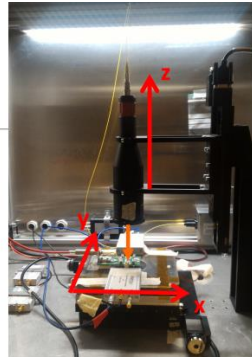
$$G(l, w, t) = G_{LET}(l) R(w, l) T(t) \rightarrow \text{Gaussian}$$

$$G_{LET}(l) = a_1 + a_2 l + a_3 e^{a_4 l} + k' [c_1 (c_2 + c_3 l)^{c_4} + LET_f(l)]$$

Pre-Irradiation: Experimental Data (FBK UFSD2 Production)



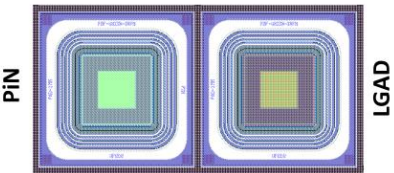
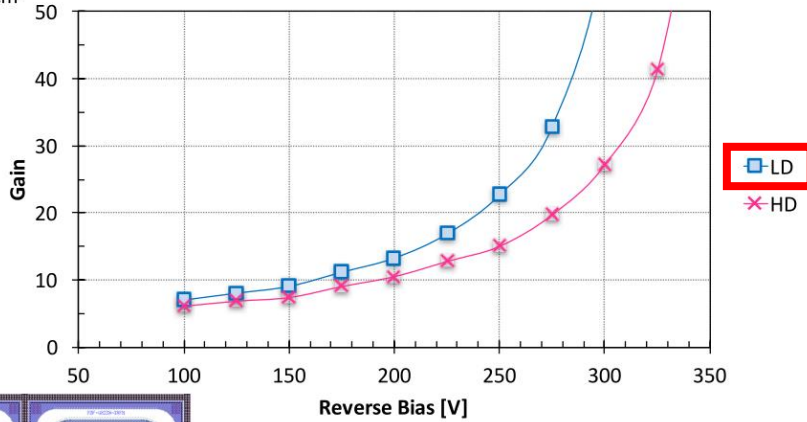
Gain Measurement – $\Phi=0$



TCT Setup from Particulars
 Pico-second IR laser at 1064 nm
 Laser spot diameter ~ 50 μ m
 Cividex Broadband Amplifier (40dB)
 Oscilloscope Lecroy 640Zi
 Room temperature
Laser attenuation 82% (3 MIP 150 fC)

LD peak: $6.1E16/cm^3 \Rightarrow 6.4E16/cm^3 (*)$
 HD peak: $4.0E16/cm^3$

Gain vs Bias - FBK UFSD2

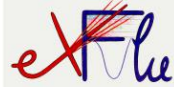


$GAIN = Charge\ LGAD / Charge\ PIN$

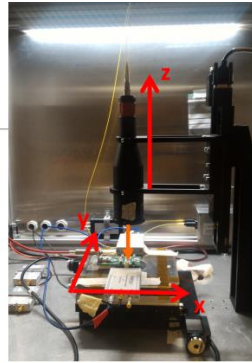
Bias [V]	W1	W8
	Gain LD	Gain HD
100	7.1	6.1
125	8.1	6.9
150	9.1	7.4
175	11.2	9.1
200	13.3	10.5
225	16.9	12.8
250	22.7	15.1
275	32.8	19.8
300	61.8	27.2
325	248.8	41.3
350	-	82.3

(*) values updated to the latest measurements – V. Sola, 20/10

Post-Irradiation: Experimental Data (FBK UFSD2 Production)

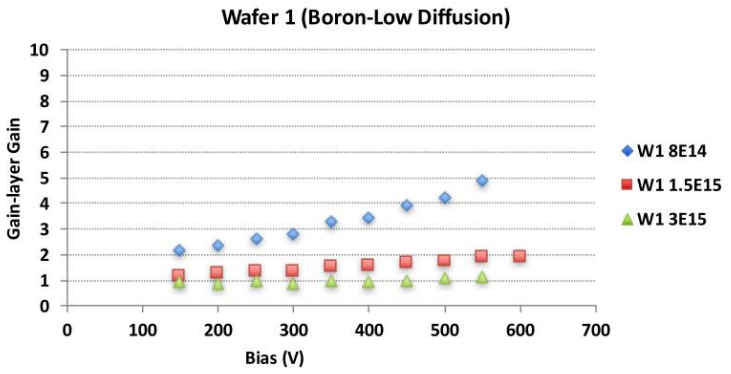


Gain Measurement – Irradiated LD



TCT Setup from Particulars
 Pico-second IR laser at 1064 nm
 Laser spot diameter ~ 50 μm
 Cividex Broadband Amplifier (40dB)
 Oscilloscope Lecroy 640Zi
 Room temperature
Laser attenuation 82% (3 MIP 150 fC)

$$c_{LD} = 3.85E-16 \text{ cm}^2$$



**GAIN = Charge LGAD / Charge PiN
 irradiated at the same fluence
 → gain from gain layer only**

Bias [V]	W1 Gain	
	Φ=8E14	Φ=1.5E15
150	2.1	1.14
200	2.4	1.26
250	2.7	1.36
300	2.8	1.37
350	3.3	1.52
400	3.4	1.54
450	3.9	1.65
500	4.2	1.74
550	4.9	1.87
600	-	1.90